



Docket No.: 21.1837

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Munetaka TAKEUCHI, et al.

Serial No. 08/889,440

Group Art Unit: 2123

RECEIVED

Confirmation No. 3473

FEB 2 6 2002

Filed: July 8, 1997

Examiner: H. Jones

**Technology Center 2100** 

For:

APPARATUS AND METHOD FOR SIMULATING PHENOMENA OF A PARTICLE OF

SUBSTRATE PARTICLES AND ADSORBATE PARTICLES

## AMENDMENT AFTER FINAL REJECTION

**Assistant Commissioner for Patents** Washington, D.C. 20231

Attention: BOX AF

Sir:

This is in response to the Office Action mailed September 24, 2001, and having a period for response set to expire on December 24, 2001. A Petition for a two-month extension of time, together with the requisite fee for same, is submitted herewith, thereby extending the period for response to February 24, 2002.

Reconsideration of the claims is respectfully requested. The following remarks are respectfully submitted.

## IN THE CLAIMS:

Please AMEND the claims as follows:

For the convenience of the Examiner, all the pending claims are set forth below, whether or not the claims are amended herein.

(FOUR TIMES AMENDED) An apparatus for simulating phenomena of a particle formed of adsorbate particles and substrate particles, comprising:

a kinetic condition setting unit which sets information for defining a plurality of generation